

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:)
Applicants: Massimiliano CAVALLINI et al)
Ser. No.: unknown)Group Art Unit: unknown
Filed: unknown)Examiner: unknown
For: "METHOD FOR MANUFACTURING AND")

Assistant Commissioner for Patents

Washington D.C. 20231 USA

MAIL STOP: P.C.T.

Sir,

INFORMATION DISCLOSURE STATEMENT

Applicants herewith enclose copies of the prior art references which have been cited in the International Search Report issued for the counterpart PCT Application which contains subject matter equivalent to that of the present application. The references submitted herewith for consideration are listed on the attached form PTO-1449.

A copy of the International Search Report (in English) is herewith provided which indicates the degree of relevancy found by the European Patent Office of each reference, so as to comply with the requirements of 37 CFR § 1.98(a)(3), according to the Commissioner's Comment 68, 1135 Off. gaz. Pat. Office 13,20 (Feb. 4, 1992), and as set forth in MPEP 609 part A(3).

A copy of the Annex to the International Search Report is also enclosed, which indicates the patent family members of the patent documents cited in the Search Report.

Respectfully submitted,



GUIDO MODIANO (Reg. No. 19,928)
Agent for the Applicants

Date: February 11, 2005
Address: Via Meravigli 16, 20123 MILAN-ITALY
Telephone: (from USA) (011)(39)(02)869-2442
Telefax: (from USA)(011)(39)(02)863-860

Encl.: -Form PTO-1449.
-Copy of International Search Report.
-Cited references.

JC14 Rec'd PCT/PTO 23 MAR 2005

FORM PTO-1449 (REV. 7-80)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			ATTY. DOCKET No. 39907/GM/lp		APPLICATION No. Still unknown		10/528775	
INFORMATION DISCLOSURE STATEMENT (use several sheets if necessary)					APPLICANTS Massimiliano CAVALLINI - Fabio BISCARINI					
					FILING DATE Still unknown		GROUP ART UNIT Still unknown			
U.S. PATENT DOCUMENTS										
*EXAMINER INITIAL	AA	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE			
	AA									
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FOREIGN PATENT DOCUMENTS										
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO			
	AL	A- 96/29629	09-1996	WIPO						
	AM									
	AN									
	AO									
	AP									
OTHER PRIOR ART (including Author, Title, Date, Pertinent Pages, Etc.)										
	AR	B. MESSER ET AL: "Microchannel networks for Nanowire Patterning" J. AM.CHEM. SOC., vol. 122, 29 September 2000 (2000-09-29), pages 10232-10233, XP002274037 the whole document								
	AS	O. CHERNIAVSKAYA ET AL.: "Edge Transfer Lithography of Molecular and Nanoparticle Materials" LANGMUIR (USA), LANGMUIR, AMERICAN CHEM. SOC, USA, vol. 18, 9 August 2002 (2002-08-09), pages 7029-77034, XP002274038 ISSN: 0743-7463 the whole document								
	AT	XIA Y ET AL: "SOFT LITHOGRAPHY ANNUAL REVIEW OF MATERIALS SCIENCE, ANNUAL REVIEWS INC., PALO ALTO, CA, US, vol. 28, 1998, pages 153-184, XP009023786 ISSN: 0084-6600 page 173 - page 174; figure 5d								
EXAMINER					DATE CONSIDERED					
* EXAMINER: Initial if reference considered, whether or not criteria is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant(s).										

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FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
	AL						
	AM						
	AN						
	AO						
	AP						
OTHER PRIOR ART (including Author, Title, Date, Pertinent Pages, Etc.)							
	AR		CHOU S Y ET AL: "LITHOGRAPHY INDUCED SELF-CONSTRUCTION OF POLYMER MICROSTRUCTURES FOR RESISTLESS PATTERNING" APPLIED PHYSICS LETTERS, AMERICAN INSTITUTE OF PHYSICS. NEW YORK, US, vol. 75, no. 7, 16 August 1999 (1999-08-16), pages 1004-1006, XP000875558 ISSN: 0003-6951				
	AS		DESHPANDE P ET AL: "Lithographically induced self-assembly of microstructures with a liquid-filled gap between the mask and polymer surface" J. VAC SCI. TECHNOL. B, MICROELECTRON. NANOMETER STRUCT. (USA), JOURNAL OF VACUUM SCIENCE & TECHNOLOGY B (MICROELECTRONICS AND NANOMETER STRUCTURES), NOV. 2001, AIP FOR AMERICAN VACUUM SOC, USA, vol. 19, no. 6, December 2001 (2001-12), pages 2741-2744, XP002274039 ISSN: 0734-211X cited in the application				
	AT						
EXAMINER				DATE CONSIDERED			
* EXAMINER: Initial if reference considered, whether or not criteria is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant(s).							